

First Announcement

Israeli BEAMeeting 2018 at Weizmann



Time: December 3rd (full day) & December 4th (half day)

Place: Weizmann Institute in Rehovot, meeting room will to be announced

Like in past year, Weizmann has taken initiative to organize (with contribution of GenISys) a purely technical workshop to discuss advanced e-beam lithography and share experiences within the Israeli e-beam lithography community. The overall program is being finalized but topics will range from:

- Process Calibration and Correction
- Exposure optimization (fracturing, field positioning/ordering, exposure order within the field)
- SEM metrology Software using ProSem
- BEAMER for laser writer and optical lithography
- Users presentations

In the **Users Presentations**... users are invited to present their own application, solution and needs.

If you wish to join the meeting and are not yet registered, please do so by e-mail to

Diana.Mahalu@weizmann.ac.il

Looking forward to seeing you at Weizmann Institute in Rehovot soon

The Weizmann & GenISys Team

